

WHAT IS CLAIMED IS:

1. A drop ejector, comprising:
a flow path in which fluid is pressurized to eject drops from a nozzle opening, and proximate the nozzle opening, a plurality of projections extending transversely to the plane of the nozzle opening.
2. The drop ejector of claim 1 wherein the nozzle opening is surrounded by projections.
3. The drop ejector of claim 1 wherein the projections are posts.
4. The drop ejector of claim 1 wherein the projections are wall-shaped.
5. The drop ejector of claim 1 wherein the projections are arranged in a pattern.
6. The drop ejector of claim 5 wherein the pattern defines an array of rows and columns.
7. The drop ejector of claim 5 wherein the pattern defines an arc.
8. The drop ejector of claim 5, wherein the pattern defines concentric ink-collection spaces.
9. The drop ejector of claim 1 wherein the projections have a width that is about twice the nozzle opening width or less.
10. The drop ejector of claim 1 wherein the spacing between the projections and the perimeter of the nozzle opening is about 20% of the nozzle opening width or greater.
11. The drop ejector of claim 1 wherein the spacing between projections is about twice the nozzle width or less.

12. The drop ejector of claim 1 wherein the number of the projections is four or greater.

13. The drop ejector of claim 1 wherein the height of the projections is substantially equal to the plane of the nozzle opening.

14. The drop ejector of claim 1 wherein the height of the projections is below the plane of nozzle opening.

15. The drop ejector of claim 1 wherein the height of the projections is above the plane of the nozzle opening.

16. The drop ejector of claim 1 wherein the nozzle opening and projections are defined in a common body.

17. The drop ejector of claim 16 wherein the body is a silicon material.

18. The drop ejector of claim 1 including a channel proximate the projections.

19. The drop ejector of claim 1 including a vacuum source or wicking material proximate the projections.

20. The drop ejector of claim 1 wherein the nozzle opening is disposed in a well and the well includes said projections.

21. The drop ejector of claim 1 wherein the nozzle opening is disposed on a platform and the projections are disposed proximate the platform.

22. The drop ejector of claim 1 including a plurality of nozzle openings and proximate each of the nozzle openings a plurality of projections, said nozzle openings and said projections defined in a common body.

23. The drop ejector of claim 1 wherein the nozzle opening width is about 200 micron or less.

24. The drop ejector of claim 1 including a piezoelectric actuator.

25. A drop ejector comprising:
a flow path in which fluid is pressurized for ejection through a nozzle opening, and proximate said nozzle opening, at least four posts extending transversely to the plane of said nozzle opening, said posts and said nozzle opening being defined in a common body.

26. The drop ejector of claim 25 wherein the spacing between said posts is about 10% of the nozzle opening width or greater and twice the nozzle opening width or less.

27. The drop ejector of claim 25 wherein the projections have a width that is about twice the nozzle opening or less.

28. A method of fluid ejection, comprising:
providing a printhead including a flow path in which fluid is pressurized for ejection through a nozzle opening, and proximate the nozzle opening a plurality of projections extending transversely to the plane of the nozzle opening, the projections defining a space transverse to the nozzle opening,

providing a fluid that is wicked by capillary forces into the space defined by said projections, and

ejecting said fluid through said nozzle opening by pressurizing said fluid in said flow path.

29. The method of claim 28 wherein the fluid has a surface tension of about 20-50 dynes/cm.
30. The method of claim 28 wherein the fluid has a viscosity of about 1 to 40 centipoise.
31. A drop ejector, comprising:
a flow path in which fluid is pressurized to eject drops from a nozzle opening, and proximate the nozzle opening, a plurality of projections extending transversely to the plane of the nozzle opening, wherein the nozzle opening and projections are defined in a common body fabricated from a silicon material and wherein the nozzle opening is disposed on a platform and the projections are disposed proximate the platform.